

Description of Service		Service Unit	Cost / Unit (CDN \$)		
			Internal (uOttawa)	External - Academic	External - Non-academic
1	SEM imaging using Raith Pioneer or Gemini500 SEM <i>Includes technologist time</i>	Hour	40	80	240
2	E-beam lithography using Raith Pioneer <i>Includes technologist time</i>	Hour	To be negotiated		
3	Etching using SAMCO <i>Includes technologist time and process gases</i>	Hour	30	60	180
4	Metal deposition using Angstrom Evaporator <i>Includes technologist time and common metals (except precious metals)</i>	Run	100	150	200
5	Wet processing <i>Includes technologist time and common consumables</i>	Hour	40	80	240
6	Metrology work (AFM, Elipsometer, Metricon, Profilometer) <i>Includes technologist time</i>	Hour	40	80	240
7	Post-processing (wire bonding, solder reflow) and sample preparation <i>Includes technologist time</i>	Hour	40	80	240
8	ORION NanoFab inspection / microscopy <i>Includes technologist time</i>	Hour	60	120	240
9	ORION NanoFab processing <i>Includes technologist time</i>	Hour	To be negotiated		
10	NanoFab Package: Unlimited access to all labs and all tools for three personnel <i>Includes technologist time for training users</i>	Year	5,500*	11,000	To be negotiated
11	Metrology Package: Unlimited access to all metrology and microscopy tools for three personnel <i>Includes technologist time for training users</i>	Year	1,500*	3,000	To be negotiated
12	Unlimited access to wet chemistry lab for chemical storage and use of fume hood and wet benches by qualified students and personnel	Year	Free	1,000	To be negotiated

*Can be prorated for 4-month terms

Please note:

- We reserve the right to remove user access when deemed necessary.
- Process knowledge is a collaborative process. The CRPuO is a multi-user facility, therefore, process knowledge is to be shared and made available to other users upon request.
- Training on a tool by a technologist is only provided to users who subscribe to service options #10, 11 or 12.